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APPLICATION NO.	I	ILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/683,985	3,985 03/08/2002		Steven H. Voldman	BUR920020014	2597
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Please find below and/or attached an Office communication concerning this application or proceeding.

		H'A
	Application No.	Applicant(s)
Office Action Summany	09/683,985	VOLDMAN, STEVEN H.
Office Action Summary	Examiner	Art Unit
The MAIL INC DATE of this communication are	ori nadav	2811
The MAILING DATE of this communication app Period for Reply	bears on the cover sheet with the	ne correspondence address
A SHORTENED STATUTORY PERIOD FOR REPL THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a repl - If NO period for reply is specified above, the maximum statutory period of the period for reply within the set or extended period for reply will, by statute any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply ly within the statutory minimum of thirty (30 will apply and will expire SIX (6) MONTHS accuse the application to become ABAND	be timely filed) days will be considered timely. from the mailing date of this communication. ONED (35 U.S.C. § 133).
Status		
1) Responsive to communication(s) filed on <u>06 M</u> 2a) This action is FINAL . 2b) This 3) Since this application is in condition for alloware closed in accordance with the practice under <u>B</u>	s action is non-final. nce except for formal matters,	•
Disposition of Claims		
4) ⊠ Claim(s) <u>26-42</u> is/are pending in the applicatio 4a) Of the above claim(s) is/are withdra 5) □ Claim(s) is/are allowed. 6) ⊠ Claim(s) <u>26-42</u> is/are rejected. 7) □ Claim(s) is/are objected to. 8) □ Claim(s) are subject to restriction and/or	wn from consideration.	
Application Papers		
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) accomposed and applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Examine 11.	eepted or b) objected to by to drawing(s) be held in abeyance. tion is required if the drawing(s) is	See 37 CFR 1.85(a). s objected to. See 37 CFR 1.121(d).
Priority under 35 U.S.C. § 119		
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority application from the International Burea * See the attached detailed Office action for a list	ts have been received. ts have been received in Appli hity documents have been rec u (PCT Rule 17.2(a)).	cation No eived in this National Stage
Attachment(s) 1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date		nary (PTO-413) ail Date nal Patent Application (PTO-152)

Application/Control Number: 09/683,985

Art Unit: 2811

DETAILED ACTION

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 26, 28, 35, 37-39 and 41-42 are rejected under 35 U.S.C. 102(b) as being anticipated by Beasom (5,841,169).

Beasom teaches in figure 2 and related text a method of forming a diode, comprising the steps of forming an anode 202 of a first conductivity type and a cathode 204 of a second conductivity type disposed below said anode on a substrate 201 without removing and replacing any portion of said substrate, wherein at least one of said cathode and anode comprise a plurality 207, 202 of vertically abutting diffusion regions; and etching said substrate (column 4, lines 14-53) to form a plurality of isolation regions 209, 219, said cathode and anode being disposed between adjacent ones of said plurality of isolation regions, said plurality of isolation regions extending deeper into said substrate that said cathode and said anode.

Regarding claim 28, Beasom teaches in figure 2 and related text isolation regions comprise a plurality of insulation-filled trenches having sidewalls that are tapered.

Regarding claim 35, Beasom teaches in figure 2 and related text the step of forming said anode comprises the steps of:

forming a first doped region 202 abutting said cathode; and

forming a second doped region 207 on a surface of said substrate, said second doped region having a higher concentration of dopant than said first doped region.

Regarding claim 37, Beasom teaches in figure 2 and related text the steps of forming a plurality of diffusion regions 214, 215 of said second conductivity type on a surface of said substrate.

Regarding claim 38, Beasom teaches in figure 2 and related text the step of forming a plurality of second isolation regions 209, 219 that separate said plurality of diffusion regions from said cathode.

Regarding claims 39 and 41-42, Beasom teaches in figure 2 and related text said cathode being in electrical contact with said substrate, wherein a junction formed between said anode and said cathode is bounded by said adjacent ones of said plurality of isolation regions, and wherein said substrate comprises a single crystal material.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 29 and 31-33 are rejected under 35 U.S.C. 103(a) as being unpatentable over Beasom.

Regarding claim 29, Beasom teaches in figure 2 and related text teaches substantially the entire claimed structure, as applied to claim 26 above, except the step of forming a second doped region of said second conductivity type disposed below said first doped region and contacting said substrate, wherein said first and second doped regions having different dopant concentrations.

Beasom teaches in figure 4 and related text the step of forming a cathode comprises forming a first doped region 403 of a second conductivity type abutting said anode 402; and forming a second doped region 404 of said second conductivity type abutting and disposed below said first doped region and contacting said substrate 401, said first and second doped regions having different dopant concentrations. It would have been obvious to a person of ordinary skill in the art at the time the invention was made to use the step of forming said cathode comprises forming a first doped region 204 of a second doped region of said second conductivity type abutting and disposed below said first doped region and contacting said substrate, wherein said first and second doped

regions having different dopant concentrations in Beasom's device in order to minimize the isolation leakage of the device.

Although Beasom does not explicitly state that layers 407, 402, 403 and 404 form a diode, layers 407, 402, 403 and 404 form a PN junction, and thus forming a diode.

Regarding claims 31 and 32, Beasom teaches in figure 2 and related text isolation regions are formed by a process comprising the steps of etching said substrate to form trenches and depositing at least one insulator and a fill material. Beasom does not teach removing portions of said insulator outside of said trenches. It would have been obvious to a person of ordinary skill in the art at the time the invention was made to remove portions of said insulator outside of said trenches in order to form the device as depicted in figure 2 of Beasom.

Regarding claim 33, Beasom teaches in figure 2 and related text the step of forming said cathode further comprises the step of forming a third doped region 206 disposed between said first doped region and said second doped region.

Claims 27 and 30 are rejected under 35 U.S.C. 103(a) as being unpatentable over Beasom in view of Mack et al. (4,736,271).

Regarding claim 27, Beasom teaches in figure 2 and related text teaches substantially the entire claimed structure, as applied to claim 26 above, except a plurality of insulation-filled trenches having sidewalls that are substantially vertical.

Mack et al. Teach in figure 11, a plurality of insulation-filled structures having sidewalls that are substantially vertical. It would have been obvious to a person of ordinary skill in the art at the time the invention was made to form the plurality of insulation-filled trenches of Beasom's device with sidewalls that are substantially vertical in order to simplify the processing steps of making the device.

Regarding claim 30, Beasom teaches in figure 2 and related text teaches substantially the entire claimed structure, as applied to claims 26 and 29 above, except forming a second pair of isolation structures between said adjacent isolation regions and said anode.

Mack et al. teach in figure 11 forming a second pair of isolation structures 30 between said adjacent isolation regions 30 and anode 54, 60. It would have been obvious to a person of ordinary skill in the art at the time the invention was made to form a second pair of isolation structures between said adjacent isolation regions and said anode in Beasom's device in order to provide better electrical isolation for the anode.

Claims 34, 36 and 40 are rejected under 35 U.S.C. 103(a) as being unpatentable over Beasom in view of Robinson et al. (5,268,316).

Beasom teaches in figure 2 and related text teaches substantially the entire claimed structure, as applied to claims 26, 33 and 35 above, except a third doped region comprises a retrograde-doped region. Robinson et al. teach a third doped region comprises a retrograde-doped region (column 3, lines 36-47). It would have been

obvious to a person of ordinary skill in the art at the time the invention was made to form a third doped region comprises a retrograde-doped region in Beasom's device in order to provide low-reverse leakage, a relatively low voltage turn-on, and low series resistance for the current path from the junction to the diode contact.

Regarding claim 40, Robinson et al. teach in figure 8 and related text a cathode is disposed entirely below an anode 6. It would have been obvious to a person of ordinary skill in the art at the time the invention was made to form the cathode entirely below the anode in Beasom's device in order to improve the characteristics of the device.

Response to Arguments

Applicant argues that Beasom does not form an anode and a cathode on a substrate without removing and replacing any portion of said substrate, because Beasom removes an entire portion of the single crystal substrate where the diode regions are subsequently formed and fills the region with polysilicon.

Beasom teaches in figure 2 and related text forming an anode 202 of a first conductivity type and a cathode 204 of a second conductivity type on substrate 201, which is located below regions 208. No part of that substrate 201 is neither removed nor replaced. Therefore, Beasom teaches forming an anode and a cathode on a substrate without removing and replacing any portion of said substrate, as claimed. Note that the broad recitation of the claim does not require the device to be provided with an original substrate, not heavily doped with an anode and a cathode. Then,

doping said original substrate to form an anode and a cathode without removing and replacing any portion of said original substrate.

Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

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Papers related to this application may be submitted to Technology center (TC) 2800 by facsimile transmission. Papers should be faxed to TC 2800 via the TC 2800 Fax center located in Crystal Plaza 4, room 4-C23. The faxing of such papers must conform with the notice published in the Official Gazette, 1096 OG 30 (November 15, 1989). The Group 2811 Fax Center number is (703) 308-7722 and 308-7724. The Group 2811 Fax Center is to be used only for papers related to Group 2811 applications.

Any inquiry concerning this communication or any earlier communication from the Examiner should be directed to *Examiner Nadav* whose telephone number is **(571) 272-1660**. The Examiner is in the Office generally between the hours of 7 AM to 4 PM (Eastern Standard Time) Monday through Friday.

Any inquiry of a general nature or relating to the status of this application should be directed to the **Technology Center Receptionists** whose telephone number is **308-0956**

O.N. 6/9/05 ORI NADAV
PRIMARY EXAMINER
TECHNOLOGY CENTER 2800